



IFW

PATENT
Customer No. 22,852
Attorney Docket No. 4329.2821-01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
)	
Riichiro TAKAHASHI et al.)	Group Art Unit: 1752
)	
Application No.: 10/824,482)	Examiner: Richard L. Schilling
)	
Filed: April 15, 2004)	Confirmation No.: 6514
)	
For: ALKALINE SOLUTION AND)	
MANUFACTURING METHOD, AND)	
ALKALINE SOLUTION APPLIED TO)	
PATTERN FORMING METHOD,)	
RESIST FILM REMOVING METHOD,)	
SOLUTION APPLICATION METHOD,)	
SUBSTRATE TREATMENT METHOD,)	
SOLUTION SUPPLY METHOD, AND)	
SEMICONDUCTOR DEVICE)	
MANUFACTURING METHOD)	

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

REPLY TO OFFICE ACTION

In reply to the Office Action mailed January 26, 2006, please amend the
above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims in this paper.

Remarks follow the amendment sections of this paper.